



09-01-03

2814#

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of: Ajit P. Paranjpe et al.
Serial No.: 09/864,714
Filing Date: May 23, 2001
Group Art Unit: 2814
Examiner: Rao, Shrinivas H.
Title: *Atomic Layer Deposition For Fabricating Thin Films*

#8/B
marsha
5/7/03

Box: Amendments – Fee
Commissioner for Patents
Washington, D.C. 20231

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Shannon Judice
Shannon Judice

4/30/03
Date of Signature

RESPONSE TO OFFICE ACTION

Dear Sir:

In response to the Office Action mailed January 15, 2003 (Paper No. 6), Applicants respectfully request that the Examiner reconsider application in view of the following amendments and remarks. The amendments are formatted and presented in accordance with the Revised Format for Amendments promulgated earlier in 2003 by the U.S. Patent and Trademark Office.

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